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Piezoelectric Thin Film MEMS

Guest Editor:

Dr. Takeshi Kobayashi
National Institute of Advanced Industrial Science and Technology, Tokyo, Japan

Deadline for manuscript submissions:
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Message from the Guest Editor

Piezoelectric MEMS are succesufully commercialized as ink-jet heads and actuators. Moreover, they have attracted more and more attention for the application to optical scanners, ultrasonic sensors, speakers, and so on. In this Special Issue, *Micromachines* invites original research papers related to piezoelectric MEMS, including piezoelectric thin films, fabrication processes, evaluations, and devices.

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Editor-in-Chief

Prof. Dr. Nam-Trung Nguyen
Queensland Quantum and Advanced Technologies Research Institute, Griffith University, West Creek Road, Nathan, QLD 4111, Australia

Message from the Editor-in-Chief

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Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
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micromachines@mdpi.com
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